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MIXING APPARATUS OF CHEMICAL FOR SEMICONDUCTOR

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Abstract of JP 61118127 (A)

PURPOSE:To reduce the contamination by foreign matter and to obtain homogeneous composition by providing a means for sucking a liq. in a mixing vessel and a filter means for removing foreign matter in the lig., and furnishing a circulating passage for circulating the lig, in the mixing vessel through the means, CONSTITUTION: Hydrogen peroxide soln, is supplied to the second mixing vessel 87 housed in the second mixing box from the second storage vessel 22 by using high-pressure gas as the driving source through a branch pipe 51b from a lig. feed pipeline 51 on the opening and closing valve 88 side, a spiral pipe, and an inlet pipe. Sulfuric acid is simultaneously supplied from the third storage vessel 23 through a lig, feed pipe 91 having an opening and closing valve 90, the respective supplies are measured by a platform balance 92. and both chemicals are mixed in a specified ratio .: The lig, mixture is circulated through the inside of a circulating passage 96 including a circulated and delivery pump 93, a lig. filter 94, and a heat exchanger 95, and the agitation, filtration, and temp. regulation are carried out.

